

<b>Report Title:</b>	AD7810/11/12/23 Transfer to TSMC
<b>Report Number:</b>	7976
<b>Revision:</b>	В
Date:	21 December 2009



### Summary

This report documents the successful completion of the reliability qualification requirements for release of the AD7810, AD7823, AD7811 and AD7812 product in a 8-miniSOIC, 16-SOIC\_N, 8-SOIC\_N and 20-SOIC\_W package. The AD7810, AD7823, AD7811 and AD7812 are high speed, low power, 10-bit A/D converter, high speed, low power, converters.

### **Table 1: AD7812 Product Characteristics**

Die/Fab	
Device / Die ID	G042B
Die Size (mm)	2.04 x 2.19
Wafer Fabrication Site	TSMC 2A 6"
Wafer Fabrication Process	0.60um DPDM CMOS
Transistor Count	5 thousand
Passivation Layer	undoped-oxide/SiN
Bond Pad Metal Composition	AlCu
Maximum Current Density (mA/µm)	0.12

20-SOIC_W 13.00 x 7.60 x 2.35 Amkor-P				
Amkor-P				
Sumitomo 6600H				
Gold				
1.20				
Ablestik 84-1LMIS R4				
Copper				
Tin Plate				
1				
260				



# **Table 2: AD7811 Product Characteristics**

Die/Fab	
Device / Die ID	G0412B
Die Size (mm)	2.04 x 2.19
Wafer Fabrication Site	TSMC 2A 6"
Wafer Fabrication Process	0.60um DPDM CMOS
Transistor Count	5 thousand
Passivation Layer	undoped-oxide/SiN
Bond Pad Metal Composition	AlCu
Maximum Current Density (mA/µm)	0.12

16-SOIC_N				
10.00 x 4.00 x 1.75				
Carsem-M				
Sumitomo 6600H				
Gold Tanaka M3				
1.20				
Ablestik 84-1LMIS R4				
Copper				
Tin Plate				
1				
260				



# Table 3: AD7810 Product Characteristics

#### Die/Fab

Device / Die ID	G05B				
Die Size (mm)	1.42 x 2.06				
Wafer Fabrication Site	TSMC 2A 6"				
Wafer Fabrication Process	0.60um DPDM CMOS				
Transistor Count	2889				
Passivation Layer	undoped-oxide/SiN				
Bond Pad Metal Composition AlCu					
Maximum Current Density (mA/µm)	0.13				

8-MINI_SOIC				
3.00 x 3.00 x 1.00				
Carsem-M				
Sumitomo 6600				
Gold Tanaka M3				
1.00				
Ablestik 84-1LMI				
Copper				
Tin Plate				
1				
260				



# Table 4: AD7823 Product Characteristics

#### Die/Fab

Device / Die ID	G051B				
Die Size (mm)	1.42 x 2.06				
Wafer Fabrication Site TSMC 2A 6"					
Wafer Fabrication Process	0.60um DPDM CMOS				
Transistor Count	2889				
Passivation Layer	undoped-oxide/SiN				
Bond Pad Metal Composition AlCu					
Maximum Current Density (mA/µm)	0.13				

Available Package	8-SOIC_N				
Body Size (mm)	5.00 x 4.00 x 1.75				
Assembly Location	Carsem-M				
Molding Compound	Sumitomo 6600H				
Wire Type	Gold Tanaka M3				
Wire Diameter (mils)	1.30				
Die Attach	Ablestik 84-1LMIS R4				
Lead Frame Material	Copper				
Lead Finish	Tin Plate				
Moisture Sensitivity Level	1				
Maximum Peak Reflow Temperature (°C)	260				



### **Description / Results of Tests Performed**

Tables 5 and 6 provide a description of the qualification tests conducted and the associated test results for products manufactured on the same technologies as described in Tables 1, 2, 3 and 4. All devices were electrically tested before and after each stress. Any device that did not meet all electrical data sheet limits following stressing would be considered a valid (stress-attributable) failure unless there was conclusive evidence to indicate otherwise.

Test Name	Spec	Conditions	Device	Package	Lot #	Sample Size	Qty. Failures
Autoclave (AC)	JESD22- A102	121°C 100%RH 2atm 168 hours	ADM202E	Carsem-M 16-SOIC_N	R86152.1	45	0
Autoclave (AC) <sup>1</sup>	JESD22- A102	121°C 100%RH 2atm 96 hours	ADM3202	Carsem-M 16-SOIC_N	Q7498.82	50	0
Biased HAST (HAST) <sup>1</sup>	JESD22- A110	130°C 85%RH 2atm, Biased 96 hours	ADM202E	Carsem-M 16-SOIC_N	R86153.1	45	0
Biased HAST (HAST) <sup>1</sup>	JESD22- A110	130°C 85%RH 2atm, Biased 96 hours	AD7707	Amkor-P 20-SOIC_W	AB60669.1	50	0
Solder Heat Resistance (SHR) <sup>1</sup>	ADI-0049	See Footer	ADM202E	Carsem-M 16-SOIC_N	R86176.1	10	0
Solder Heat Resistance (SHR) <sup>1</sup>	ADI-0049	See Footer	ADM3202	Carsem-M 16-SOIC_N	Q7498.305	15	0
Temperature Cycling (TC) <sup>1</sup>	JESD22- A104	-65°C / +150°C 500 cycles	ADM202E	Carsem-M 16-SOIC_N	R86154.1	45	0
Temperature Cycling (TC) <sup>1</sup>	JESD22- A104	-65°C / +150°C 500 cycles	ADM3202	Carsem-M 16-SOIC_N	Q7498.303	50	0

1) These Samples were subjected to preconditioning (per J-STD-020 Level 1) prior to the start of the stress test. Level 1 preconditioning consists of the following: Bake: 24 hrs @ 125°C, Soak: Unbiased Soak: 168 hrs @ 85°C, 85%RH, Reflow: 3 passes through an oven with a peak temperature of 260°C.

Table 6: Fab Qualification Test Results

Table 6. Fab Qualification Test Results							
Test Name	Spec	Conditions	Device	Fab Process	Lot #	Sample Size	Qty. Failures
					AA88950.1	400	0
			AD7314		AA88950.2	400	0
		405%0 40			AA88950.3	210	0
Early Life	MIL-STD-			TSMC 2A	n91512.7	110	0
Failure Rate	883, Method	125°C 48 hours		6" 0.6µm	N91512.4	150	0
(ELFR)	1015	nouis	ADM1029	CMOS	N91512.5	150	0
	1010		ADIVIT029		N91512.6	150	0
					O91631.1	255	0
					O91631.2	255	0
					F124480.4	45	0
		130°C	ADV7175	TSMC 2A	F124481.4	45	0
Biased HAST	JESD22-	85%RH		6" 0.6µm	F124482.4	45	0
(HAST)	A110	2atm, Biased		CMOS	F117464.5	45	0
		96 hours	AD73322	0003	F125657.9	45	0
					F117966.7	45	0
		130°C 85%RH	AD9281	TSMC 2A	J31360.1	77	0
Biased HAST	JESD22-			6" 0.6µm	J31358.1	77	0
(HAST) <sup>1</sup>	A110	2atm, Biased 96 hours	AD9201	CMOS	J31359.1	77	0
		125°C ∢ Tj ∢ 135°C,	AD7015		OF45308.4	45	0
					OF46725.4	45	0
High					OF46726.4	45	0
	Biased 1,000			F102031.4	76	0	
Temperature		hours	ADM1025	TSMC 2A 6" 0.6µm CMOS	F102041.4	77	0
Operating	A108				F102042.4	77	0
Life (HTOL)	Allo		_		AA88981.1	50	0
		150°C ‹ Tj ‹			R86144.1	45	0
		175°C, Biased 1,000 hours	AD7314		R86343.1	45	0
High	JESD22- A103		AD6421	TOMO DA	F108185.22	45	0
					F108185.28	45	0
Temperature				TSMC 2A	F108185.34	45	0
Storage Life			AD73322	6" 0.6µm CMOS	F117464.7	45	0
(HTSL)				CIVIUS	F117966.4	45	0
					F121100.11	45	0

1) These Samples were subjected to preconditioning (per J-STD-020 Level 1) prior to the start of the stress test. Level 1 preconditioning consists of the following: Bake: 24 hrs @ 125°C, Soak: Unbiased Soak: 168 hrs @ 85°C, 85%RH, Reflow: 3 passes through an oven with a peak temperature of 260°C.

Samples of the many devices manufactured with these package and process technologies are continuously undergoing reliability evaluation as part of the ADI Reliability Monitor Program. Additional qualification data is available on Analog Devices' web site.





## **ESD Test Results**

The results of Human Body Model (HBM) and Field Induced Charge Device Model (FICDM) ESD testing are summarized in the ESD Results Table. ADI measures ESD results using stringent test procedures based on the specifications listed. Any comparison with another supplier's results should ensure that the same ESD test procedures have been used. For further details, please see the EOS/ESD chapter of the ADI Reliability Handbook (available via the 'Quality and Reliability' link at the Analog Devices Website (Analog Website).

ESD Model	Device	Package	ESD Test Spec	RC Network	Highest Pass Level	First Fail Level	Class
FICDM	AD7812	20-SOIC_W	ANSI/ESD	1Ω, Cpkg	±1500V	NA	C6
	AD7811	16-SOIC_N	STM5.3.1-	_	±1000V	±1500V	C5
	AD7810	8-PDIP	1999		±1500V	NA	C6
HBM	AD7812	20-SOIC_W	ANSI/ESD	1.5kΩ,	±2500V	±3000V	2
	AD7810	8-PDIP	STM5.1- 2007	100pF	±3000V	±3500V	2

### **Table 7: ESD Test Results**

### Latch-Up Test Results

Six AD7812 devices were subjected to latch-up testing per JEDEC Standard JESD78, Class II, Level A, at  $T_A=25^{\circ}$ C. All parts were electrically tested at room temperatures pre- and post stress. All six devices passed.

## Approvals

This report has been approved by electronic means (4.0). Reliability Engineer: Fergus Downey

## **Additional Information**

Data sheets and other additional information are available on Analog Devices' web site: <u>Analog</u> <u>Website</u>